### PCT

# WORLD INTELLECTUAL PROPERTY ORGANIZATION International Bureau



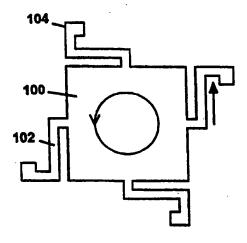
## INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(51) International Patent Classification <sup>6</sup> : G02B 26/02	A3	(11) International Publication Number: WO 99/52006 (43) International Publication Date: 14 October 1999 (14.10.99)
(21) International Application Number: PCT/US  (22) International Filing Date: 1 April 1999 (c)  (30) Priority Data: 09/056,975 8 April 1998 (08.04.98)  (63) Related by Continuation (CON) or Continuation-in (CIP) to Earlier Application  US 09/056,97  Filed on 8 April 1998 (c)  (71) Applicant (for all designated States except US): EINC. [US/US]; Suite 501, 354 Congress Street, Boto 02110–1237 (US).  (72) Inventor; and  (75) Inventor/Applicant (for US only): MILES, Mark, W. Suite 501, 354 Congress Street, Boston, MA 02 (US).	01.04.9  In-Part  75 (COI 08.04.9  ETALO Ston, M	Published With international search report. Before the expiration of the time limit for amending the claim and to be republished in the event of the receipt of amendments  (88) Date of publication of the international search report: 29 December 1999 (29.12.99  N) N, A
(74) Agent: FEIGENBAUM, David, L.; Fish & Richard 225 Franklin Street, Boston, MA 02110-2804 (US		

### (54) Title: INTERFEROMETRIC MODULATION OF RADIATION

#### (57) Abstract

The invention features an interferometric modulator comprising a cavity defined by two walls. At least two arms connect the two walls to permit motion of the walls relative to each other. The two arms are configured and attached to a first one of the walls in a manner that enables mechanical stress in the first wall to be relieved by motion of the first wall essentially within the plane of the first wall.



### FOR THE PURPOSES OF INFORMATION ONLY

Codes used to identify States party to the PCT on the front pages of pamphlets publishing international applications under the PCT.

AL	Albania	ES	Spain	LS	Lesotho	SI	Slovenia
AM	Armenia	FI	Finland	LT	Lithuania	SK	Slovakia
AT	Austria	FR	France	LU	Luxembourg	SN	Senegal
ΑU	Australia	GA	Gabon	LV	Latvia	SZ	Swaziland
ΑZ	Azerbaijan	GB	United Kingdom	MC	Monaco	TD	Chad
BA	Bosnia and Herzegovina	GE	Georgia	MD	Republic of Moldova	TG	Togo
BB	Barbados	GH	Ghana	MG	Madagascar	TJ	Tajikistan
BE	Belgium	GN	Guinea	MK	The former Yugoslav	TM	Turkmenistan
BF	Burkina Faso	GR	Greece		Republic of Macedonia	TR	Turkey
BG	Bulgaria	HU	Hungary	ML	Mali	TT	Trinidad and Tobago
BJ	Benin	Œ	Ireland	MN	Mongolia	UA	Ukraine
BR	Brazil	IL.	Israel	MR	Mauritania	UG	Uganda
BY	Belarus	IS	Iceland	MW	Malawi	US	United States of America
ÇA	Canada	IT	Italy	MX	Mexico	UZ	Uzbekistan
CF	Central African Republic	JP	Japan	NE	Niger	VN	Viet Nam
CG	Congo	KE	Kenya	NL	Netherlands	YÜ	Yugoslavia
CH	Switzerland	KG	Kyrgyzstan	NO	Norway	zw	Zimbabwe
CI	Côte d'Ivoire	KP	Democratic People's	NZ	New Zealand		
CM	Cameroon		Republic of Korea	PL	Poland		
CN	China	KR	Republic of Korea	PT	Portugal		
CU	Cuba	KZ	Kazakstan	RO	Romania		
CZ	Czech Republic	LC	Saint Lucia	RU	Russian Federation		
DE	Germany	LI	Liechtenstein	SD	Sudan		
DK	Denmark	LK	Sri Lanka	SE	Sweden		
EE	Estonia	LR	Liberia	SG	Singapore		

Internatic Application No PCT/US 99/07271

a classif IPC 6	G02B26/02		
According to	International Patent Classification (IPC) or to both national classification	n and IPC	
B. FIELDS S			
Minimum doe IPC 6	cumentation searched (classification system followed by classification GO2B B81C GO9F	symbols)	
	ion searched other than minimum documentation to the extent that sucl		ed
Electronic da	ata base consulted during the international search (name of data base	and, where practical, search terms used)	
C. DOCUME	ENTS CONSIDERED TO BE RELEVANT		
Category *	Citation of document, with indication, where appropriate, of the relevant	ant passages	Relevant to claim No.
X	WO 95 30924 A (ETALON INC ;MILES N (US)) 16 November 1995 (1995-11-10	MARK W	1-8,10, 11,15, 23,24
A	page 33, line 20 -page 34, line 19 28	5; figure	14
	•	/	
İ		ţ	
		į	
	•		
		L. L.	
X Fur	ther documents are listed in the continuation of box C.	X Patent family members are listed in	ennex.
° Special o	ategories of cited documents:	T later document published after the intern	ational filing date
'A' docum	nent defining the general state of the art which is not idered to be of particular relevance	or priority date and not in conflict with the cited to understand the principle or theor	ry underlying the
.E. earlier	document but published on or after the international	invention "X" document of particular relevance; the clai	med invention
"I " dooun	date nent which may throw doubts on priority claim(s) or	cannot be considered novel or cannot be involve an inventive step when the docu	e considered to ment is taken alone
l whic	h is cited to establish the publication date of another ion or other special reason (as specified)	"Y" document of particular relevance; the claim cannot be considered to involve an inve	ntive step when the
.O. qoon	ment referring to an oral disclosure, use, exhibition or r means	document is combined with one or more ments, such combination being obvious	other such docu-
.b. qocat	r means ment published prior to the international filing date but than the priority date claimed	in the art. "&" document member of the same patent fa	
1	e actual completion of the international search	Date of mailing of the international search	h report
	12 August 1999	1 0. 11. 199	9
Name and	d mailing address of the ISA	Authorized officer	
	European Patent Office, P.B. 5818 Patentiaan 2 NL - 2280 HV Rijswijk		
1	Tel. (+31-70) 340-2040, Tx. 31 651 epo ni,	SCHEU, M	

1

Internat Application No
PCT/US 99/07271

N COOMMENTS CONCINEDED TO BE BELEVANT	
tion) DOCUMENTS CONSIDERED TO BE RELEVANT	10
Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
ARATANI K ET AL: "PROCESS AND DESIGN CONSIDERATIONS FOR SURFACE MICROMACHINED BEAMS FOR A TUNEABLE INTERFEROMETER ARRAY IN SILICON" PROCEEDINGS OF THE WORKSHOP ON MICRO ELECTRO MECHANICAL SYSTEMS (ME, FORT LAUDERDALE, FEB. 7 - 10, 1993, no. WORKSHOP 6, 7 February 1993 (1993-02-07), pages 230-235, XP000366885 INSTITUTE OF ELECTRICAL AND ELECTRONICS ENGINEERS ISBN: 0-7803-0957-X page 232	1-8,10,
GOOSSEN K W ET AL: "SILICON MODULATOR BASED ON MECHANICALLY-ACTIVE ANTI-REFLECTION LAYER WITH 1 MBIT/SEC CAPABILITY FOR FIBER-IN-THE-LOOP APPLICATIONS" IEEE PHOTONICS TECHNOLOGY LETTERS, vol. 6, no. 9, 1 September 1994 (1994-09-01), pages 1119-1121, XP000468079 ISSN: 1041-1135 the whole document	1-7, 9-11,15
EP 0 667 548 A (AT & T CORP) 16 August 1995 (1995-08-16) column 3, line 12 - line 35 column 4, line 54 -column 6, line 30; figure 2	1-7, 9-11,15
	CONSIDERATIONS FOR SURFACE MICROMACHINED BEAMS FOR A TUNEABLE INTERFEROMETER ARRAY IN SILICON" PROCEEDINGS OF THE WORKSHOP ON MICRO ELECTRO MECHANICAL SYSTEMS (ME, FORT LAUDERDALE, FEB. 7 - 10, 1993, no. WORKSHOP 6, 7 February 1993 (1993-02-07), pages 230-235, XP000366885 INSTITUTE OF ELECTRICAL AND ELECTRONICS ENGINEERS ISBN: 0-7803-0957-X page 232  GOOSSEN K W ET AL: "SILICON MODULATOR BASED ON MECHANICALLY-ACTIVE ANTI-REFLECTION LAYER WITH 1 MBIT/SEC CAPABILITY FOR FIBER-IN-THE-LOOP APPLICATIONS" IEEE PHOTONICS TECHNOLOGY LETTERS, vol. 6, no. 9, 1 September 1994 (1994-09-01), pages 1119-1121, XP000468079 ISSN: 1041-1135 the whole document  EP 0 667 548 A (AT & T CORP) 16 August 1995 (1995-08-16) column 3, line 12 - line 35 column 4, line 54 -column 6, line 30;

International application No. PCT/US 99/07271

Box I Observations where certain claims were found unsearchable (Continuation of Item 1 of first sheet)
This International Search Report has not been established in respect of certain claims under Article 17(2)(a) for the following reasons:
1. Claims Nos.: because they relate to subject matter not required to be searched by this Authority, namely:
Claims Nos.: because they relate to parts of the International Application that do not comply with the prescribed requirements to such an extent that no meaningful International Search can be carried out, specifically:
3. Claims Nos.: because they are dependent claims and are not drafted in accordance with the second and third sentences of Rule 6.4(a).
Box II Observations where unity of invention is lacking (Continuation of item 2 of first sheet)
This International Searching Authority found multiple inventions in this international application, as follows:
As all required additional search fees were timely paid by the applicant, this International Search Report covers all searchable claims.
2. As all searchable claims could be searched without effort justifying an additional fee, this Authority did not invite payment of any additional fee.
3. As only some of the required additional search fees were timely paid by the applicant, this International Search Report covers only those claims for which fees were paid, specifically claims Nos.:
4. No required additional search fees were timely paid by the applicant. Consequently, this International Search Report is restricted to the invention first mentioned in the claims; it is covered by claims Nos.:  1-15,23,24
Remark on Protest  The additional search fees were accompanied by the applicant's protest.  No protest accompanied the payment of additional search fees.

### FURTHER INFORMATION CONTINUED FROM PCT/ISA/ 210

1. Claims: 1-15,23,24

An interferometric modulator comprising a cavity defined by two walls wherein the first wall is movable relative to the second wall and within the plane of the first wall

2. Claims: 16-18

Interferometric modulator comprising three walls and control circuitry for driving at least one of three walls

3. Claims: 19-20

an interference modulator comprising spacers mounted to form part of one of the walls

4. Claims: 21,22,25

Interference modulator comprising means to control the response time of the modulator  $% \left( 1\right) =\left\{ 1\right\} =\left\{ 1$ 

5. Claim: 26

Interferomtric modulator comprising a charge deposition mitigating device

6. Claims: 27-32

An interferometric modulator, comprising walls and a support and at least one of the walls or the support comprising at least two materials

7. Claims: 33-38,44-48

A method of etching and patterning a microelectromechanical structure

8. Claims: 39-43

a method of making arrays of microelectromechanical structure on a production line

internation on patent family members

Interna' 1 Application No PCT/US 99/07271

Patent document cited in search report		Publication date		Patent family member(s)	Publication date
WO 9530924	A	16-11-1995	US EP JP	5835255 A 0801766 A 10500224 T	10-11-1998 22-10-1997 06-01-1998
EP 0667548	A	16-08-1995	US CA US US	5500761 A 2137063 A 5654819 A 5589974 A	19-03-1996 28-07-1995 05-08-1997 31-12-1996